



- (3506) 250/281 250/288
 - (3) ("4570068" | "4667100" | "5157260").PN.
 - (474) (250/281 250/288) and heater
 - (4910) remov\$ and electrospray
 - (328) removable and electrospray
 - (2) removable near3 electrospray
 - (3) ("5306412" | "5788166" | "6127680").PN.
 - (376) apci and electrospray
 - (460) 250/455.11
 - (113) 250/455.11 and electron
 - (6) ("4075496" | "4201920" | "4252413" | "4281251" | "4492873" | "5004926").PN.
 - (1) wo99/00801
 - (0) "9900801"
 - (5) anderberg and irradiation
 - (8) anderberg and irradiation
 - (9) "9900801"
 - (31) 250/455.11 and electron and (computer microprocessor)
 - (325) (arc near3 chamber) and alumina
 - (19) (arc near3 chamber) and (alumina near3 insulat\$4)
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USPAT: US-PGPUB: EPO: JPO: DERWENT: IBM ☒ Plurals

Default operator: ☒ Highlight all hit terms initially

11 and alumina

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|----|-------------------------------------|--------------------------|-------------------|------------|-------|--|------------|---------------------------|----------------|--------------|
| 1 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030136918 A1 | 20030724 | 11 | SOFT IONIZATION DEVICE AND APPLICATIONS THEREOF | 250/423R | | | Hartle |
| 2 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030127433 A1 | 20030710 | 11 | Automated electrode replacement apparatus for a plasma processing | 219/121.56 | 250/423R; 313/359.1; | | Sirkis. |
| 3 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030122089 A1 | 20030703 | 15 | Ion sources for ion implantation apparatus | 250/492.21 | 250/423R; 250/425 | | Murre |
| 4 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030042436 A1 | 20030306 | 49 | Discharge electrode and discharge electrode manufacturing method | 250/493.1 | | | Horj, T |
| 5 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030042435 A1 | 20030306 | 9 | Powdered far-infrared radiator and method of making the same | 250/493.1 | | | Imai, I |
| 6 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030038245 A1 | 20030227 | 13 | Field ionizing elements and applications thereof | 250/423R | 250/287; 250/288; | | Hartle |
| 7 | <input type="checkbox"/> | <input type="checkbox"/> | US 20020056816 A1 | 20020516 | 18 | Surface plasmon enhanced illumination system | 250/493.1 | | | Stark, Hazar |
| 8 | <input type="checkbox"/> | <input type="checkbox"/> | US 6617810 B2 | 20030909 | 11 | Multi-stage cavity cyclotron resonance accelerators | 315/500 | 250/292; 250/423R; | | Symon |
| 9 | <input type="checkbox"/> | <input type="checkbox"/> | US 6617806 B2 | 20030909 | 21 | High brightness microwave lamp | 315/248 | 313/113; 315/39 | | Kirkpa |
| 10 | <input type="checkbox"/> | <input type="checkbox"/> | US 6610986 B2 | 20030826 | 10 | Soft ionization device and applications thereof | 250/423R | 250/286; 250/287; | | Hartle |
| 11 | <input type="checkbox"/> | <input type="checkbox"/> | US 6597004 B2 | 20030722 | 9 | Powdered far-infrared radiator and method of making the same | 250/493.1 | 250/495.1; 252/500; | | Imai, I |
| 12 | <input type="checkbox"/> | <input type="checkbox"/> | US 6566257 B2 | 20030520 | 12 | Method for producing semiconductor device | 438/682 | 257/E21.199; 257/E21.334; | | Sueyo |
| 13 | <input type="checkbox"/> | <input type="checkbox"/> | US 6562418 B2 | 20030513 | 4 | Microwave processing of pressed boron powders for use as cathodes | 427/580 | 419/37; 419/38; | | Morro |
| 14 | <input type="checkbox"/> | <input type="checkbox"/> | US 6559443 B2 | 20030506 | 14 | Ionization apparatus and ionization method for mass spectrometry | 250/288 | 250/281; 250/282; | | Shlok; |
| 15 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6547458 B1 | 20030415 | 25 | Optimized optical system design for endpoint detection | 396/611 | 156/118; 156/250; | | Janos |
| 16 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6541917 B1 | 20030401 | 11 | Section of pipe for a gas treatment device and device incorporating su | 315/111.21 | 118/723MW | | Rosta et al. |
| 17 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6538251 B1 | 20030325 | 15 | Radiation source assembly and transducer for analyzing gases or o | 250/343 | 250/339.06; 250/341.7; | | Weck; |
| 18 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6531704 B2 | 20030311 | 27 | Nanotechnology for engineering the performance of substances | 250/493.1 | 205/766 | | Yadav |
| 19 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6525480 B1 | 20030225 | 18 | Low power, linear geometry hall plasma source with an open electro | 315/111.21 | 250/423R; 313/231.31; | | Hargu |
| 20 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6507142 B1 | 20030114 | 13 | Plume shield for ion accelerators | 313/239 | 250/423R; | | Tilley, |